Abstract

An inspection system configured to inspect a substrate while performing temperature control is provided. The inspection system comprises a substrate holder configured to hold the substrate, a detector configured to supply an inspection power to an electrode portion of the substrate, and a controller. The detector includes a temperature estimation part configured to estimate a junction temperature of a junction portion provided at the substrate. The controller is configured to perform supplying the inspection power to the substrate, acquiring information on the junction temperature after the supply of the inspection power is stopped, determining an offset temperature of the substrate holder based on the information on the junction temperature, adjusting the temperature of the substrate holder based on a control temperature offset by the offset temperature, and supplying the inspection power to the substrate to inspect the substrate after the temperature of the substrate holder is adjusted.